Global sensitivity analysis of a model for silicon nanoparticle synthesis

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Abstract

This paper presents a global sensitivity analysis of the detailed population balance model for silicon nanoparticle synthesis of Menz & Kraft (2013, *Combustion* & *Flame*, **160**:947–958). The model consists of a gas-phase kinetic model, fully coupled with a particle population balance. The sensitivity of the model to its seven adjusted parameters was analysed in this work using a High Dimensional Model Representation (HDMR). An algorithm is implemented to generate response surface polynomials with automatically selected order based-on their coefficient of determination. A response surface is generated for 19 different experimental cases across a range of process conditions and reactor configurations. This enables the sensitivity of individual experiments to certain parameters to be assessed. The HDMR reveals that particle size was most sensitive to the heterogeneous growth process, while the particle size distribution width is also strongly dependent on the rate of nucleation.

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1 Introduction

Knowledge of the properties of silicon has underpinned the revolution of information technology. A great deal of study has therefore been undertaken into its synthesis, purification and resultant properties. Silicon nanoparticles were first made in the late 1970's [28] and since then, have been the subject of considerable work towards improving their manufacture and identifying potential applications.

Gas-phase, laser and plasma synthesis of particles are the most common methods with which silicon nanoparticles are manufactured [21]. In general, these processes begin with silane (SiH₄), which may be decomposed by thermal, laser or microwave radiation [4, 14, 29]. The decomposition of silane forms reactive silicon hydrides, which combine with each other to nucleate into silicon nanoparticles [38].

Various models–from gas-phase kinetic to particle population balances–have been proposed to describe the formation of nanoparticles from silane [24, 30, 38]. In all of these models, it is common to find model parameters which have uncertain values. Examples include empirical expressions for sintering [6, 24, 36].

In some cases, it is possible to estimate these values by trial-and-error [15]. However, for a non-linear model with many unknown parameters, this process becomes difficult. Systematic parameter estimation can be used to move from by-hand guesswork to computer-based solutions. For example, a model implemented in Excel[®] could use the GOALSEEK or SOLVER functionality to arrive at better input parameter values.

There are a range of optimisation techniques which can be used to improve model values [17]. Low-discrepancy sampling can be used to evaluate the model response over a space of parameter values [3]. Gradient-search methods such as the simultaneous perturbation stochastic approximation (SPSA) algorithm can locate local and global minima [6, 24]. Response surfaces, or surrogate models, can also be generated from low-discrepancy sampling, yielding a computationally-efficient approximations of the true model [13]. Then, Markov Chain Monte Carlo (MCMC) sampling and Bayesian analyses are often applied to assess the credible regions in which the optimal parameter values may lie [13, 27].

Recently, a detailed model for silicon nanoparticle synthesis was presented [22]. The model incorporates a gas-phase kinetic model, fully-coupled with a particle population balance. In its original development, systematic parameter estimation was used to optimise the model's seven parameters with respect to experimental data across a range of different process conditions. However, the relative importance of each parameter in the objective function was not quantitatively addressed in this work. Nor was the influence of particular experiments on the objective function. These open questions should be addressed in order to further assess the physical relevance of the model as well as its sensitivity to input parameters.

Due to the variety of solution methods for population balance models, there are a range of different approaches for studying the sensitivity of the model's parameters. Vikhansky and Kraft [40, 41] demonstrated use of a gradient search method to assess the sensitivity of stochastic (Monte Carlo) solution methodologies as applied to population balances equations. In complex models, a simple scan of the parameter space can also be used [18, 36]. An excellent review of sensitivity analysis methods is given by Tomlin [39].



Figure 1: Schematic of the information transfer between the models, the parameter estimation methodology and experimental sources. The quantities highlighted in red refer to the adjusted parameters.

The purpose of this work is to investigate the estimated parameters in model of Menz and Kraft [22] for silicon nanoparticle synthesis. A global sensitivity analysis will be conducted using HDMR response surfaces in order to elucidate the influence of each parameter in the optimisation. This will illustrate an alternative approach through which sensitivity analyses can be conducted, not as yet used in this community. Finally, the sensitivity analysis will also be applied to gain additional physical insight into the model.

The structure of this paper is as follows. A brief description of the model is given in Section 2, including the gas-phase (Section 2.1) and the population balance (Section 2.2). The techniques used for parameter estimation and sensitivity analysis are presented in Section 3. The results from the sensitivity analysis are given and discussed in Section 4.

2 Model

The model for silicon nanoparticle synthesis is composed of a gas-phase kinetic model and a particle population balance model. A full formulation of the model is given in [22], however a brief description is given here. In the original development of the model, parameter estimation was used to optimise gas-phase and particle-phase parameters with respect to experimental results from the literature. This process is illustrated in Figure 1.

2.1 Gas-phase model

The bulk decomposition of silane can be described as the bimolecular expression [32]:

$$SiH_4 + M \rightarrow SiH_2 + H_2 + M \tag{1}$$

where M is a third body. It is well-understood that silane decomposition proceeds through a series of intermediate gas-phase species, such as silylene (SiH_2) and higher silenes/silanes. For this model, the mechanism of Ho et al. [11] is adopted. The mechanism has eight core reactions, mostly described by Lindemann falloff expressions. Pre-exponential factors for five of the reactions were adjusted from their initial values. The equations describing the rate of change of chemical species due to these reactions are solved using a conventional ordinary differential equation (ODE) solver.

2.2 Particle population balance model

The binary-tree particle model of Sander et al. [34] is used in this work. Each particle P_q is represented as:

$$P_q = P_q \left(p_1, \dots, p_{n_a}, \mathbf{C} \right) \tag{2}$$

where particle P_q contains n_q primary particles p_x . **C** is a lower-diagonal matrix representing the common surface area between two primary particles. Each primary particle is described by the number of silicon atoms η_{si} and hydrogen atoms η_{H} :

$$p_x = p_x(\eta_{\rm Si}, \eta_{\rm H}) \tag{3}$$

All other properties of the particle are derived from this representation. A full mathematical formulation of the model is given in [22] and [35]. Particle processes can change the type-space of a particle in a variety of different ways. The processes included in the model for silicon nanoparticle synthesis are listed in Table 1 and described below.

Inception

A collision of a silylene (e.g. SiH_2) species with another silylene or silene species will form a particle. The rate of inception dependent on the critical nucleus diameter, a quantity which may be estimated using macroscopic properties of silicon and the process conditions [22]. When the diameter of the particle to be incepted is greater than the critical diameter, the rate of inception is calculated using the transition regime coagulation kernel [25].

Surface reaction

In this context, surface reactions refer to the heterogeneous reaction of silanes $(SiH_4, Si_2H_6, Si_3H_8)$ on the particle surface. Silanes must proceed through an energy barrier in order for the reaction to proceed [12]. Hence, the rate of surface reaction is represented by a Arrhenius rate constant [11]. It is also proportional to the particle surface area [22]. In the population balance model, a surface reaction event also causes rounding of joined primaries. This is represented by the transformation $\mathbf{C} \to \mathbf{C}'$.

Process	Reaction					
Inception	$\mathrm{Si}_{i}\mathrm{H}_{j}\mathrm{B} + \mathrm{Si}_{k}\mathrm{H}_{l} \rightarrow P(\eta_{\mathrm{Si}} = i + k, \eta_{\mathrm{H}} = j + l, \mathbf{C})$					
Surface reaction	$P(\dots, p_x(\eta_{\mathrm{Si}}, \eta_{\mathrm{H}}), \dots, \mathbf{C}) + \mathrm{Si}_i \mathrm{H}_{2i+2}$ $\rightarrow P(\dots, p_x(\eta_{\mathrm{Si}} + i, \eta_{\mathrm{H}} + 2), \dots, \mathbf{C}') + i \mathrm{H}_2$					
Condensation $(j \neq i+2)$	$P(\dots, p_x(\boldsymbol{\eta}_{\mathrm{Si}}, \boldsymbol{\eta}_{\mathrm{H}}), \dots, \mathbf{C}) + \mathrm{Si}_i \mathrm{H}_j$ $\rightarrow P(\dots, p_x(\boldsymbol{\eta}_{\mathrm{Si}} + i, \boldsymbol{\eta}_{\mathrm{H}} + j), \dots, \mathbf{C}')$					
Hydrogen release	$P(\dots, p_x(\boldsymbol{\eta}_{\mathrm{Si}}, \boldsymbol{\eta}_{\mathrm{H}}), \dots, \mathbf{C})$ $\rightarrow P(\dots, p_x(\boldsymbol{\eta}_{\mathrm{Si}}, \boldsymbol{\eta}_{\mathrm{H}} - 2), \dots, \mathbf{C}) + \mathrm{H}_2$					
Coagulation	$P_q(p_1,\ldots,p_{n_q},\mathbf{C}_q)+P_r(p_1,\ldots,p_{n_r},\mathbf{C}_r)$ $\rightarrow P_s(p_1,\ldots,p_{n_q},p_{n_q+1},\ldots,p_{n_q+n_s},\mathbf{C}_s)$					
Sintering $(n' \le n)$	$P(p_1,\ldots,p_n,\mathbf{C})\to P(p_1,\ldots,p_{n'},\mathbf{C}')$					

Table 1: Particle processes included in the population balance model.

Condensation

Silenes (e.g. H_2SiSiH_2) and silylenes (e.g. SiH_2) react with particle surfaces through a condensation process. That is, their rate of reaction is given by a collision kernel, here the free-molecular kernel. It is assumed that they stick with probability 1.0 and that there is no energy barrier to reaction.

Hydrogen release

Particles must release hydrogen in order to maintain a stable crystal structure when growing. The rate of hydrogen desorption is proportional to the coverage of hydrogen on the particle surface as well as an Arrhenius rate constant [37]. In this model, the coverage is approximated by the ratio of number of hydrogen atoms to number of silicon atoms in each particle.

Coagulation

The rate of coagulation is dependent on the Knudsen number, and is given by the transition kernel. In a coagulation event, the particle trees are added to each other, preserving the particle size and connectivity information held in the state-space.

Sintering

Adjacent primary particles may sinter through a grain-boundary diffusion process. The common surface element of connected primaries p_x and p_y , C_{xy} , will decrease until it is sufficiently close to the equivalent spherical area of the two primaries. Then, the primaries are merged into a single primary particle. This occurs as a continuous process throughout the tree of primaries in the computational particle.

A stochastic numerical method is employed to solve the population balance model. This method has been well-documented [1, 26, 35] and takes advantage of various features

-;	Sumbol	Dhaga	Decomination
J	Symbol	Fliase	Description
1	$A_{1,\mathrm{LP}}$	Gas	Low-pressure pre-exponential factor for Reaction 1
2	$A_{2,\mathrm{LP}}$	Gas	Low-pressure pre-exponential factor for Reaction 2
3	$A_{3,\mathrm{LP}}$	Gas	Low-pressure pre-exponential factor for Reaction 3
4	$A_{5,\mathrm{LP}}$	Gas	Low-pressure pre-exponential factor for Reaction 5
5	$A_{8,rev}$	Gas	Reverse pre-exponential factor for Reaction 8
6	$A_{\mathrm{SR,SiH}_4}$	Particle	Pre-exponential factor for SiH ₄ surface reactions
7	$A_{ m H_2}$	Particle	Pre-exponential factor for H ₂ release

Table 2: Overview of adjusted parameters.

such as linear process deferment [31], a binary tree cache [10] and the concept of majorant rates with fictitious jumps [7] to accelerate the solution of the population balance model. Coupling with the gas-phase is accomplished using the technique of operator splitting [5, 35].

3 Parameter estimation

In the original development of the model, parameter estimation was used to obtain suitable fit of the model response to experimental results. Seven parameters were identified for estimation. The physical and numerical meaning of these parameters are given in Figure 1 and Table 2 respectively. This results in a parameter vector given by:

$$\theta = (A_{1,\text{LP}}, A_{2,\text{LP}}, A_{3,\text{LP}}, A_{5,\text{LP}}, A_{8,\text{rev}}, A_{\text{SR,SiH}_4}, A_{\text{H}_2})$$
(4)

The optimal set of parameters (θ^*) is reliant on measuring the distance of the model response from the experimental results. To do this, a least-squares objective function, $\Phi(\theta)$, was formulated:

$$\Phi(\theta) = \sum_{i=1}^{N_{exp}} \left(\eta_i^{exp} - \eta_i^{sim}(\theta) \right)^2$$
(5)

where η_i^{exp} is an experimental response, and η_i^{sim} is obtained from the model for the corresponding experiment. The number of experiments used in the optimisation is given by N_{exp} . A staged optimisation procedure was used to find the optimal set of parameters $\hat{\theta}$, with numerical results given in [22].

3.1 High Dimensional Model Representation

In this work, we are interested in the sensitivity of the model and its parameters near the optimal found in previous work. The global sensitivities can be calculated from a High Dimensional Model Representation (HDMR) [33]. A HDMR is a form of response surface, or surrogate model. Its main feature is the decomposition of the full function for

a response η^{sim} into a sum of functions that only depend on the input variables such that:

$$\eta^{\text{sim}}(\boldsymbol{\theta}) = f(\boldsymbol{\theta}) = f(\boldsymbol{\theta}) = f_0 + \sum_{i=1}^{N_{\text{param}}} f_i(\boldsymbol{\theta}_i) + \sum_{i=1}^{N_{\text{param}}} \sum_{j=i+1}^{N_{\text{param}}} f_{ij}(\boldsymbol{\theta}_i, \boldsymbol{\theta}_j) + \dots + f_{12\dots N_{\text{param}}}(\boldsymbol{\theta}_1, \boldsymbol{\theta}_2, \dots, \boldsymbol{\theta}_{N_{\text{param}}})$$
(6)

where N_{param} is the number of parameters, *i* and *j* index the input parameters and f_0 is the mean value of $f(\theta)$. In practical applications, it is possible to truncate the above expression to second-order terms [33]. The order of a group of terms is given the symbol *d*, with the maximum order considered d_{max} . Thus, a response is approximated by:

$$\boldsymbol{\eta}^{\text{sim}}(\boldsymbol{\theta}) \approx f(\boldsymbol{\theta}) = f_0 + \underbrace{\sum_{i=1}^{N_{\text{param}}} f_i(\boldsymbol{\theta}_i)}_{\text{first-order terms}} + \underbrace{\sum_{i=1}^{N_{\text{param}}} \sum_{j=i+1}^{N_{\text{param}}} f_{ij}(\boldsymbol{\theta}_i, \boldsymbol{\theta}_j)}_{\text{second-order terms}}$$
(7)

3.1.1 Calculation of sensitivities

The global sensitivities can be determined by considering the variance of the model response. The first-order variance, $\sigma_{\eta_{\text{sim},i}}^2$, and second-order variance, $\sigma_{\eta_{\text{sim},ij}}^2$, both contribute to this quantity, given by:

$$\sigma_{\eta^{\rm sim},i}^2 = \int_{-1}^{1} f_i(\theta_i)^2 \mathrm{d}\theta_i \tag{8}$$

$$\sigma_{\eta^{\rm sim},ij}^2 = \int_{-1}^1 \int_{-1}^1 f_{ij}(\theta_i,\theta_j)^2 \mathrm{d}\theta_i \mathrm{d}\theta_j \tag{9}$$

where the integrals are taken over the upper- and lower-bounds chosen for the parameters, here assumed to be normalised to be [-1,1]. This is consistent with other experimental design literature [2, 20]. The total variance is then given by:

$$\sigma_{\eta^{\rm sim}}^2 = \sum_{i=1}^{N_{\rm param}} \sigma_{\eta^{\rm sim},i}^2 + \sum_{i=1}^{N_{\rm param}} \sum_{j=i+1}^{N_{\rm param}} \sigma_{\eta^{\rm sim},ij}^2$$
(10)

Then, the first- and second-order normalised sensitivities are given by:

$$S_{\eta^{\rm sim}}(\theta_i) = \frac{\sigma_{\eta^{\rm sim},i}^2}{\sigma_{\eta^{\rm sim}}^2} \text{ and } S_{\eta^{\rm sim}}(\theta_i,\theta_j) = \frac{\sigma_{\eta^{\rm sim},ij}^2}{\sigma_{\eta^{\rm sim}}^2}$$
(11)

That is, $S_{\eta^{sim}}(\theta_i)$ represents the first-order sensitivity of model response η^{sim} to parameter θ_i , and so on. These quantities can be used to compare the influence of parameters within a particular model response. To compare across model responses, the sensitivity should be converted to an absolute sensitivity. Here, the absolute sensitivity is measured by the standard deviation of the first-order model response:

$$S_{\eta^{\rm sim}}^*(\theta_i) = \sigma_{\eta^{\rm sim},i} \tag{12}$$

where $S^*_{\eta^{\text{sim}}}(\theta_i)$ has dimensions $[\eta^{\text{sim}}]$. Physically, this quantity represents the standard deviation in output response η^{sim} achievable from varying parameter θ_i within its specified bounds.



Figure 2: Algorithm for recursive fitting of the polynomials and selection of \overline{R}^2 .

3.1.2 Automatic order selection

The functions $f(\theta)$ must be determined in order to evaluate the sensitivities. These functions are decomposed into orthogonal basis functions [19], which are taken as Legendre polynomials. The coefficients of these polynomials are determined through a recursive fitting procedure. This has the advantage of being able to tailor the polynomial order to each of the interaction order functions. Similar approaches have been adopted in the work of Ziehn and Tomlin [43].

The algorithm to conduct this whole fitting process is given in Figure 2. The user specifies a maximum interaction order (d_{max}) and maximum polynomial order for each interaction order $(M_{max,d})$ and the algorithm yields the first polynomial with \overline{R}^2 above a tolerance \overline{R}^{2*} . A tolerance on the minimum improvement in \overline{R}^2 , \overline{R}^2_{min} is applied to increase the efficiency of the process. If a new iteration is found to be worse than the previous one, the new iteration is discarded and the algorithm moves onto the next interaction order.

Table 3: Experimental datasets used in the present work. d_{type} refers to the physical quantity being measured from the system: either primary (d_{pri}) or mobility (d_{mob}) diameter. The statistical quantity measured for the particle size is given in the column μ_{type} . An asterisk (*) denotes an estimated quantity.

i	Т	УSiH4	Р	τ	d_{type}	$\mu_{ ext{type}}$	$\eta_i^{\mathrm{exp},\mu}$	$\eta_i^{\mathrm{exp},\sigma}$	Ref.
-	°C	%	kPa	ms	-	-			
1	1100	0.04	2.5	80	$d_{ m pri}$	mode	26.7	1.07	[15]
2	1100	0.04	2.5	192	$d_{ m pri}$	mean	26.0	1.11	[15]
3	1100	0.125	2.5	192	$d_{ m pri}$	mean	38.0	1.28	[15]
4	1100	0.128	2.5	80	$d_{\rm pri}$	mode	31.0	1.3	[15]
5	1100	0.02	2.5	80	$d_{\rm pri}$	mode	41.0	1.06	[15]
6	1100	0.08	2.5	80	$d_{\rm pri}$	mode	24.0	1.25	[15]
7	1100	0.04	2.5	420	$d_{\rm pri}$	mode	32.5	1.10	[15]
8	900	0.04	2.5	420	$d_{\rm pri}$	mode	21.2	1.11	[15]
9	1000	0.04	2.5	420	$d_{\rm pri}$	mode	28.5	1.11	[15]
10	816	0.033	51	2600	$d_{\rm pri}$	mode	11.0	1.50^{*}	[9]
11	1047	0.033	51	2100	$d_{\rm pri}$	mode	11.0	1.55*	[9]
12	1307	0.033	51	1800	$d_{\rm pri}$	mode	15.0	1.54*	[9]
13	1200	0.01	101	1000	$d_{ m mob}$	mode	127	1.38*	[42]
14	1050	0.214	20	6	$d_{\rm pri}$	mean	43.4	-	[8] '630S'
15	1150	0.09	20	15	$d_{\rm pri}$	mean	55.4	-	[8] '631S'
16	1000	0.06	20	53	$d_{\rm pri}$	mean	23.0	-	[8] '654S'
17	800	0.001	101	900	$d_{\rm mob}$	mode	89.0	1.61*	[29]
18	800	0.0004	101	900	$d_{\rm mob}$	mode	51.0	1.55*	[29]
19	600	0.05	39	870	$d_{\rm pri}$	mean	52.0	-	[30]

3.2 Analysis procedure

There is a wealth of experimental conditions at which the silicon nanoparticle synthesis model can be evaluated [8, 9, 15, 29, 42]. These are given in Table 3. There, experiments are described by their process conditions: representative temperature (*T*), initial mole fraction of silane (y_{SiH_4}), total pressure (*P*) and residence time (τ). The resultant PSDs from such experiments, where available, are described by a modal or average particle size ($\eta_i^{\exp,\mu}$), and a geometric standard deviation ($\eta_i^{\exp,\sigma}$).

A low-discrepancy (Sobol) sequence was used to evaluate the model at points within the bounds defined for the parameters. This sequence was constructed around the parameter optimals identified in previous work [22]. The modal or mean particle size $(\eta_i^{\sin,\mu})$ and the geometric standard deviation $(\eta_i^{\sin,\sigma})$ of the ensemble were calculated at each of these points. HDMR response surfaces were determined from this data for the two PSD descriptors.

4 Results and discussion

The HDMR approach to parameter analysis yields the sensitivity of each experimental case to each parameter (first-order) or parameter pair combination (second-order). Only the first-order sensitivities will be discussed here, as it was observed that the only significant second-order interactions were composed of those which were significant in the first-order.

4.1 Breakdown of sensitivities

In Figure 3, the sensitivity of the mode or mean of a PSD is displayed. As there were 19 experimental cases, each with 7 first-order sensitivities, a representative experiment was chosen from each experiment group to simplify visualisation of data. The absolute sensitivities of the PSD mode or mean are first compared across the parameters for each of the 6 groups in Figure 3(a).

It is clearly evident that the particle size is most sensitive to $A_{\text{SR,SiH}_4}$, that is, the surface reaction process. It has the largest absolute sensitivity for each of the representative experimental cases. This confirms the importance of accurately describing surface reaction process in models for silicon nanoparticle formation. The second most sensitive parameter is $A_{1,\text{LP}}$, the silane decomposition pre-exponential. This is not surprising, as it has often been targeted for optimisation in previous studies [16, 24].

In Figure 3(b), the first-order sensitivities are compared within experiments. Again, it is evident that the surface reaction pre-exponential is the dominant parameter for all cases. However, the relative importance $A_{1,LP}$ and to a lesser extent, $A_{3,LP}$ and A_{H_2} are seen here. It is interesting to observe that A_{H_2} accounts for approximately 5% of the sensitivity for the cases of Frenklach et al. [9] and Onischuk et al. [30], as both cases were experimentally reported to yield particles with high concentrations of hydrogen.

The sensitivities are broken-down differently when considering sensitivity of the PSD's geometric standard deviation, shown in Figure 4. Again, the model is most sensitive to $A_{\text{SR,SiH}_4}$, $A_{1,\text{LP}}$ and less so $A_{3,\text{LP}}$, A_{H_2} , depicted in Figure 4(a). However, the internal breakdown of sensitivities is quite different. It is illustrated in Figure 3(b) that $A_{1,\text{LP}}$ plays an important role for all experimental cases. Since $A_{1,\text{LP}}$ has a large impact on the inception process of particles, this observation reinforces the conclusions of Nguyen and Flagan [29] and Körmer et al. [16] that controlling the nucleation rate is critical in controlling the dispersion of particles.

Further, the absolute sensitivities with respect to geometric standard deviation are generally greatest for the cases of Flint et al. [8], Nguyen and Flagan [29] and Onischuk et al. [30] (Figure 4(a)). These three cases correspond to those where aggregate particles are formed, where the coagulation rate is likely to be high. In such systems, it is common to see a spike in geometric standard deviation prior to it reaching its final value - either controlled by a finite sintering rate or primary coalescence [23]. It is therefore suggested that by varying the parameters describing inception, the PSD's geometric standard deviation has been observed at different points along this process, leading to an increased sensitivity of the distribution width for aggregate-forming cases.



(a) The absolute sensitivities of the PSD mode compared across parameter types



(b) The normalised sensitivities of the PSD mode compared across experiments

Figure 3: Comparison of the sensitivity of the PSD mode/mean (μ case) across parameter types and different representative experiments.



(a) The absolute sensitivities of the PSD geometric standard deviation compared across parameter types



(b) The normalised sensitivities of the PSD geometric standard deviation compared across experiments

Figure 4: Comparison of the sensitivity of the PSD geometric standard deviation (σ case) across parameter types and different representative experiments.

Finally, the case with the least sensitive geometric standard deviation is that of Wu et al. [42]. In this case, spherical particles are produced in a very hot reactor. It is likely that due to fast sintering [23] and strong particle nucleation [22], the system reaches the self-preserving PSD for the majority of parameter combinations. Thus, while the modal point of the PSD is very sensitive to surface growth (Figure 3(a)), the comparative width of the distribution is relatively static (Figure 3(a)).

4.2 Sensitivities as a function of process conditions

In the previous section, the sensitivity the model at specific experimental conditions was addressed. The HDMR results can also be used to investigate how sensitivity varies with the process conditions across all experiments. In order to do this, the absolute sensitivities were plotted on a bubble plot in Figure 5, where the size of the circle is proportional to the sensitivity.

The left column of Figure 5 shows the sensitivity of the particle size descriptor, while the sensitivity of the geometric standard deviation is given in the right column. The choice of temperature and initial silane pressure (Py_{SiH_4}) was made to clearly separate the experimental cases, although in practice the experiments are actually functions of more variables–such as residence time and reactor configuration–than these two. In any case, the clear importance of the surface reaction process at all process conditions is again demonstrated here.

It appears that $A_{3,LP}$ is generally more important at lower pressures. This could indicate the the reaction pathway for forming Si₂H₆ becomes more important as silane pressure decreases. This observation would be consistent with homogeneous nucleation theory, as the critical cluster size increases as the partial pressure of silicon decreases. That is, larger gas-phase clusters (e.g. Si₂H₆+) must be formed before particles are stable enough to grow. Hence, the parameter describing one of the major pathways for this process has a stronger effect on PSD characteristic at lower silane pressure.

There are also some trends within experimental cases. For example, it is evident in the cases of Körmer et al. [16] that the sensitivity with respect to geometric standard deviation is roughly inversely proportional to silane pressure, while direct proportionality is observed for PSD mode sensitivity. This phenomenon is consistent with the experiments of Körmer et al. [15], where increasing the pressure of silane would cause runaway nucleation, yielding broader PSDs and larger particles. Thus, as the pressure increases and the PSD broadens, the system nears the self-preserving distribution and the PSD's geometric standard deviation becomes insensitive to input parameters.

5 Conclusions

This paper has presented an adaptation of a High Dimensional Model Representation (HDMR) to a detailed model for silicon nanoparticle synthesis. The HDMR yielded information about the sensitivity of the model outputs to various input parameters across a range of experiments conditions and configurations. The output responses investigated



Figure 5: Global sensitivities (S^*) for $A_{1,LP}$, $A_{3,LP}$, A_{SR,SiH_4} , A_{H_2} shown as a function of process conditions. Each circle represents an experimental case (Table 3) and its diameter is proportional to the absolute sensitivity.

were the particle size and distribution width, the latter represented as geometric standard deviation.

It was found that the particle size was most sensitive to the parameter controlling the surface reaction rate. The same was observed for the geometric standard deviation, however it was also sensitive to the initial decay rate of silane. The sensitivity analysis data could also be linked to phenomena reported experimentally. For example, the model was shown to be sensitive to the hydrogen release rate in cases where high concentrations of hydrogen were experimentally reported.

The knowledge of the model's sensitivity can now be applied to embark on an experimental discrimination pathway. This can potentially indicate which experiments pull parameter optimals in which directions. Alternatively, it can show which experiments–or the model's representation of them–are incorrect. Although these aspects remain to be completed, it has been demonstrated that use of a HDMR as part of parameter estimation procedure can reveal new layers of insight from a complex model.

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